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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/785,005	02/25/2004	Shigeru Fujita	SON-2612/DIV	9742
23353 7	590 10/04/2005		EXAM	INER
RADER FISH	IMAN & GRAUER P	LLC	LE, Th	IAO X
LION BUILDI 1233 20TH ST	NG REET N.W., SUITE 501		ART UNIT	PAPER NUMBER
	N, DC 20036		2814	
			DATE MAILED: 10/04/200	5

Please find below and/or attached an Office communication concerning this application or proceeding.

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	Application No.	Applicant(s)
	· ·	
Office Action Summary	10/785,005	FUJITA, SHIGERU
cine violen cumuary	Examiner	Art Unit
The MAILING DATE of this communicat	Thao X. Le	2814
Period for Reply	ion appears on the cover sheet w	in the correspondence address
A SHORTENED STATUTORY PERIOD FOR THE MAILING DATE OF THIS COMMUNICA' - Extensions of time may be available under the provisions of 37 after SIX (6) MONTHS from the mailing date of this communication of the period for reply specified above is less than thirty (30) dated in NO period for reply is specified above, the maximum statutor Failure to reply within the set or extended period for reply will, I Any reply received by the Office later than three months after the earned patent term adjustment. See 37 CFR 1.704(b).	TION. CFR 1.136(a). In no event, however, may a ation. ys, a reply within the statutory minimum of thir y period will apply and will expire SIX (6) MOR by statute, cause the application to become Al	reply be timely filed ty (30) days will be considered timely. NTHS from the mailing date of this communication. BANDONED (35 U.S.C. § 133).
Status		
1) Responsive to communication(s) filed o	n 17 August 2005.	
·= ·		
3) Since this application is in condition for		ters, prosecution as to the merits is
closed in accordance with the practice u	*	·
Disposition of Claims		
· <u> </u>	n the application	
4) Claim(s) 1-5 and 13-16 is/are pending in 4a) Of the above claim(s) is/are wire 5) Claim(s) is/are allowed. 6) Claim(s) 1-5 and 13-16 is/are rejected. 7) Claim(s) is/are objected to. 8) Claim(s) are subject to restriction	thdrawn from consideration.	
Application Papers		
9) The specification is objected to by the Ex	kaminer.	•
10) The drawing(s) filed on is/are: a)	☐ accepted or b)☐ objected to	by the Examiner.
Applicant may not request that any objection	n to the drawing(s) be held in abeya	nce. See 37 CFR 1.85(a).
Replacement drawing sheet(s) including the 11) The oath or declaration is objected to by	•	
Priority under 35 U.S.C. § 119		
12) ☐ Acknowledgment is made of a claim for a a) ☐ All b) ☐ Some * c) ☐ None of: 1. ☐ Certified copies of the priority doc		§ 119(a)-(d) or (f).
	amonto have been received.	and the second second
<u> </u>	uments have been received in A	Application No
		· ·
2. Certified copies of the priority doc	ne priority documents have beer	· ·

Paper No(s)/Mail Date _

1) Notice of References Cited (PTO-892)

2) Notice of Draftsperson's Patent Drawing Review (PTO-948)

3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08)

4) Interview Summary (PTO-413)
Paper No(s)/Mail Date. _____.

6) Other: __

5) Notice of Informal Patent Application (PTO-152)

DETAILED ACTION

Continued Examination Under 37 CFR 1.114

1. A request for continued examination under 37 CFR 1.114, including the fee set forth in 37 CFR 1.17(e), was filed in this application after final rejection. Since this application is eligible for continued examination under 37 CFR 1.114, and the fee set forth in 37 CFR 1.17(e) has been timely paid, the finality of the previous Office action has been withdrawn pursuant to 37 CFR 1.114. Applicant's submission filed on 17 Aug. 2005 has been entered.

Claim Rejections - 35 USC § 102

- 2. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:
 - (e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.
- 3. Claims 1-4, 13-15 are rejected under 35 U.S.C. 102(e) as being anticipated by US Pub 2002/0190302 to Bojarczuk, Jr.

Regarding claim 1, Bojarczuk discloses a semiconductor device fig. 1 and 4 comprising: a semiconductor substrate 210 [0031], a high dielectric-constant film 220 [0016] on the semiconductor substrate 210, and a nitride layer 430 [0036] & [0038] on the high-dielectric-constant film 220, fig. 6, wherein the high dielectric constant film 220

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is selected from film comprised of enhanced dielectric material including Al_2O_3 and silicate [[0016] derided from said enhanced dielectric material, and film having multiple-layered structure including at least two layers (220/220), fig. 4, of said silicate film [0016].

Regarding claims 2-4, 14-15, Bojarczuk discloses the semiconductor device further comprises a p-type impurity-contained layer 240 [0009] on the nitride layer 430, fig. 4, wherein the nitride layer 430 is formed by introducing nitrogen in to the top surface portion of the high-dielectric-constant film 220 [0018], wherein the semiconductor substrate 210 is a silicon substrate [0031].

Regarding claim 13, Bojarczuk discloses a semiconductor device in fig. 1 and 4 comprising: a semiconductor substrate 210, a gate insulating film 220 on a semiconductor substrate 210, and a gate electrode 240 formed on the gate insulating film 220 and including at least a p-type impurity layer [0009] and [0042], wherein the gate insulating film includes a high-dielectric-constant film 220 and a nitride layer 430, fig. 4, on the high-dielectric-constant film 220, wherein the high dielectric constant film 220 is selected from film comprised of enhanced dielectric material of films including Al₂O₃ silicate [0016] film derived from said enhanced dielectric material, and film having multiple-layer structure of at least two layers of said silicate film [0016].

But Jeon does not expressly disclose a gate electrode 108

However, Ramkumar discloses a semiconductor device wherein

polysilicon gate layer is being doped with boron to form P-type gate, column 1

line 27-30. At the time the invention was made; it would have been obvious to

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one of ordinary skill in the art to use the p-type polysilicon gate teaching of Ramkumar with Jeon's layer 108, because it would have created a p-type gate MOSFETS.

Claim Rejections - 35 USC § 103

- 4. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 5. Claims 5 and 16 are rejected under 35 U.S.C. 103(a) as being unpatentable over US Pub 2002/0190302 to Bojarczuk, Jr.

Regarding claims 5 and 16, Bojarczuk discloses the semiconductor device wherein the p-type impurity-contained layer 240 [0009].

But Bojarczuk does not expressly disclose the boron-contained silicon layer. At the time the invention was made; it would have been obvious to one of ordinary skill in the art to use boron to created p-type silicon, because such boron doping to create a p-type layer is conventional in the art, see Ramkumar in column 1 line 27-30.

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Conclusion

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6. Any inquiry concerning this communication or earlier communications from the Examiner should be directed to Thao X. Le whose telephone number is (571) 272-1708. The examiner can normally be reached on M-F from 8:00 AM - 4:30 PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Wael M. Fahmy can be reached on (571) 272 -1705. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Thao X. Le 03 May 2005